

June 6, 2005



FOR IMMEDIATE RELEASE

ISSYS Inc. Awarded a Patent for Next-Generation, Smart Catheters

Ypsilanti, Michigan, June 6, 2005: Integrated Sensing Systems, Inc. (ISSYS) announced today that the U.S Patent Office has granted a patent entitled "Sensing Catheter System and Method of Fabrication" (US Patent No. 6,824,521) which covers the design, fabrication and manufacturing of next-generation, smart catheters based on ISSYS' proprietary micromachined miniature pressure sensors.

ISSYS' IP allows the design and low-cost manufacturing of a variety of catheters with 1 to 32 embedded sensing elements -- such as pressure, impedance, temperature -- and only 2 wires for powering, reading, and controlling of these sensing elements. Furthermore, ISSYS miniature pressure sensors are absolute sensors that will eliminate the need for a dedicated lumen in the catheter and more importantly, eliminate the expensive assembly step of accurate attachment and sealing of the pressure sensors to the catheter.

Ms. Sonbol Massoud-Ansari, ISSYS VP of Foundry Services, stated that "ISSYS technology, for the first time, allows the low-cost production of next-generation catheters. Commercializing smart catheters is not part of ISSYS current strategic business plan. ISSYS plans to license this technology to potential strategic partners. Among other ISSYS technologies available for licensing are: micromachined blades and micro-needles."

Company Background: ISSYS is a leader in advanced micromachining technologies for medical devices, microfluidic and scientific analytical sensing applications. Founded in 1995 by world-renowned leaders in MEMS technology, ISSYS is one of the oldest independent MEMS companies in the US and has been offering MEMS services longer than any other existing company in the US. ISSYS operates a "full manufacturing under one roof," multi-million-dollar, state-of-the-art MEMS fabrication facility located near Ann Arbor, Michigan. An ISO 9001:2000 certified organization, ISSYS is a vertically integrated company dedicated to developing and manufacturing system-level products based on MEMS technology (MEMS Inside). For more company, product and service information, please visit <http://www.mems-issys.com/>

Source: Integrated Sensing Systems, Inc. (ISSYS)

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